Electronic Supplementary Information for

## High-Performance Deep Ultraviolet Photodetectors Based on Few-Layer Hexagonal Boron Nitride

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**Figure S1.** The SAED patterns recorded at different locations on the same h-BN domain have identical orientation, implying the single-crystal nature of h-BN domain.



Figure S2. Schematic diagram of the h-BN transfer by a rosin-assisted wet-transfer method.



Figure S3. The EDX spectroscopy elemental mappings of B and N for the h-BN layer transferred onto a  $SiO_2/Si$  substrate.



Figure S4. Optical micrograph of the h-BN DUV photodetector.



**Figure S5.** The I-V curves of h-BN photodetectors measured in the dark. The devices were fabricated from the h-BN layers grown at different temperatures.

Materials	Cut off	Dark current	Responsivity $(\mathbf{m} \mathbf{A} / \mathbf{W})$	On/off ratio	Ref.
Diamond	225	1.1 pA/5 V	48	10 <sup>4</sup>	1
β-Ga <sub>2</sub> O <sub>3</sub>	250	1200 pA/10 V	37	10 <sup>3</sup>	2
Mg <sub>x</sub> Zn <sub>1-x</sub> O	273	20 pA/15 V	0.1	104	3
AlN	240	0.1 pA/100 V	400	/	4
SiC	310	100 pA/100 V	70	103	5
h-BN	250	200 nA/4 V	1.5	<5	6
h-BN	250	4 nA/4 V	0.09	/	7
h-BN	225	20 pA/20 V	0.1	10 <sup>3</sup>	This Work

**Table S1.** Comparison of the photoresponse parameters between the h-BN photodetectors and DUV photodetectors fabricated from other wide band gap semiconductors.

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